

<b>Notice of References Cited</b>	Application/Control No. 10/531,208	Applicant(s)/Patent Under Reexamination UEDA ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-7,013,965	03-2006	Zhong et al.	165/185
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Przybilla et al (Proceedings of SPIE, Vol.1672, Advances in Resist Technology and Processing IX (1992), pg.500-512).
	V	Niinomi et al (Proceedings of SPIE, Vol.2724, Advances in Resist Technology and Processing XIII (1996), pg.174-185).
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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